

L Number	Hits	Search Text	DB	Time stamp
1	2421	(reactor or chamber or vessel or tank) and (horizontal\$2 with flow) and ((stage or support or platen or table or susceptor or chuck) with control\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 13:10
8	652	(reactor or chamber or vessel or tank) and (horizontal\$2 with flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 13:28
15	0	(reactor or chamber or vessel or tank) same (horizontal\$2 with flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3)) not ((reactor or chamber or vessel or tank) and (horizontal\$2 with flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 13:32
22	193	(reactor or chamber or vessel or tank) same ("laminar flow") and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3)) not ((reactor or chamber or vessel or tank) and (horizontal\$2 with flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 13:38
36	77	(reactor or chamber or vessel or tank) same (laminar same flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3)) not (((reactor or chamber or vessel or tank) and (horizontal\$2 with flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3))) or ((reactor or chamber or vessel or tank) same ("laminar flow") and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3)) not ((reactor or chamber or vessel or tank) and (horizontal\$2 with flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3))))))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 13:46
43	410	(reactor or chamber or vessel or tank) same (cross with flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3)) not (((reactor or chamber or vessel or tank) and (horizontal\$2 with flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3))) or ((reactor or chamber or vessel or tank) same ("laminar flow") and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3)) not ((reactor or chamber or vessel or tank) and (horizontal\$2 with flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3)))))) or ((reactor or chamber or vessel or tank) same (laminar same flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3)) not (((reactor or chamber or vessel or tank) and (horizontal\$2 with flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3))) or ((reactor or chamber or vessel or tank) same ("laminar flow") and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3)) not ((reactor or chamber or vessel or tank) and (horizontal\$2 with flow) and ((stage or support or platen or table or susceptor or chuck) with (temperature and control\$3))))))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 14:46
50	26	"5,077,875"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 13:53
57	4	"5,405,446"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 13:54
64	3	("5288327") or ("5190592") or ("5077875")).PN.	USPAT	2003/03/28 13:54
65	554	(stage or support or platen or table or susceptor or chuck) same (temperature and control\$3 and coolant and heater)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 14:49
72	204	(stage or support or platen or table or susceptor or chuck) same (temperature and control\$3 and coolant and heater and deposit\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 14:51

79	181	((stage or support or platen or table or susceptor or chuck) same (temperature and control\$3 and coolant and heater and deposit\$3)) and (wafer or article or substrate or semiconductor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 15:14
86	2	5846375.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 15:18
93	2	5228501.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 15:32
100	2	6383330.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 15:38
107	2	5077875.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 15:43
114	0	09838215.rlan.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 15:43
121	2	us-20010032588-\$.did.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 16:04
128	135	MOCVD and laminar	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 16:22
135	14	MOCVD and (anodized adj1 aluminum)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 16:25
142	148	(horizontal with (reactor or vessel or chamber)) and (anodized adj1 aluminum)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 16:29
149	112	((horizontal with (reactor or vessel or chamber)) and (anodized adj1 aluminum)) and (wafer or article or substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 17:22
156	11	(anodized adj1 aluminum) and zervigon.xa.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/28 17:25